

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the U.S. Patent Application of

TOKMULIN et-al.



Examiner: Zervignon, R.

Serial No.: 08/860,763

Art Unit: 1763

RECEIVED

Filing Date: September 9, 1998

Docket No.: P-9701 ISK

JAN 29 2001

For: Device for Treating Planar Elements with a Plasma Jet

OFFICE OF PETITIONS

Assistant Commissioner of Patents
Washington, D.C. 20231**AMENDMENT AFTER FINAL REJECTION AND
REQUEST FOR RECONSIDERATION**

SIR:

Responsive to the Office Action mailed April 25, 2000, please amend the above identified application as follows.

IN THE CLAIMS:

Please cancel claim 4, without prejudice, add claim 14 and amend claims 2 and 5 as follows.

Claim 2, line 7, change "A plasma" (first occurrence) to -said plasma-;

line 7, before "located" insert -being-.

14. A device for treating wafers with a plasma jet, comprising a plasma jet generator; gas supplying means; a set of holders for wafers to be treated, said holders having a drive for effecting angular displacement thereof and for facing a generator plasma jet; each of the holders being made in the form of a horizontal platform mounted for rotation about an axis passing